

# FALCON ICS412

## INLINE WAFER COATING/WASHING SYSTEM

The Falcon ICS 412 inline flux coating/wafer washing system is capable of dispensing up to 4 process fluids (2 standard such as flux and bowl wash) on wafers ranging in size from 4 inches (100mm) to 12 inches (300mm). No tool changes are required when changing from 6 inch (150mm) through 12 inch (300mm) wafer sizes. With an unlimited number of recipe steps, all process parameters are fully programmable including dispense start, end, sweep and height. The servo drive spin chuck is programmable with speeds from 1 to 2000 RPM. The spin chuck vacuum system includes a fluid trap reservoir to prevent vacuum system contamination. The fully servo driven controlled inline belt transport requires no adjustments, no robot teaching, or sensor adjustments. The diagnostics mode of the software allows visual maintenance of all input, outputs, servo motors, and encoders. The engineering mode allows direct and immediate process changes in real time. Password protection allows multiple level operator use.



System facility requirements include electricity, vacuum, N2, and water. High volume vacuum exhaust is required for the washer configuration. Options include wafer wash capabilities and the ability to process up to 4 fluids.

## SPECIFICATIONS

### FEATURES

LOAD/UNLOAD BUFFERS	Belt or Robot transfer
DIRECTION OF FLOW	Bi-directional
TRANSPORT SYSTEM	Belt   Robot
AUTOMATION	SMEMA   SECS/GEM

### SUBSTRATE CAPACITY

MIN/MAX DIMENSIONS – INCH (CM)	4.9 (125) L x W min 11.8 (300) L x W max
MAXIMUM WEIGHT – LBS (KG)	1 (0.45)



**FACILITY REQUIREMENTS**

INPUT VOLTAGE (VAC)	115   220   380
INPUT AMPS RMS (A)	≤12 @ start-up ≤6 @ steady state
SYSTEM POWER (KW)	
DIMENSIONS (W x D x H)	41 x 42 x 41 inches 104 x 107 x 104 cm

For more information contact [sales@sikama.com](mailto:sales@sikama.com)